

Title (en)  
AN INSPECTION SYSTEM AND METHOD

Title (de)  
INSPEKTIONSSYSTEM UND -VERFAHREN

Title (fr)  
SYSTÈME ET PROCÉDÉ D INSPECTION

Publication  
**EP 2359122 A2 20110824 (EN)**

Application  
**EP 09794834 A 20090710**

Priority  

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Abstract (en)  
[origin: WO2010005591A2] A system and method for measuring the physical characteristics of a component where the system includes a light source, a sensing device, a reflecting device, and a retention mount. The method includes associating a component with the system such that the component is positioned within the retention mount and operating the system to cause the light source to emit a collimated light beam along a source optical path, where the collimated light beam is reflected to cause a reflected collimated light beam to propagate along a sensor optical path to be incident upon the component to produce a component silhouette where the sensing device generates data responsive to the silhouette. The image data is processed to generate resultant data responsive to the component, wherein the resultant data is further responsive to at least one of a smoothing algorithm, a functional size algorithm and a centering algorithm.

IPC 8 full level  
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